

HIGH-SPEED INSPECTION OF FLAT SUBSTRATES WITH UNDERLYING VISIBLE TOPOLOGY

Abstract of the Disclosure

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One embodiment disclosed relates to a method for inspecting a substrate. The method includes exposing the substrate to an incident beam, inducing relative motion between the incident beam and the substrate, and detecting charged particles emitted from the substrate. The relative motion is such that the beam travels over a surface of the substrate along a substantially spiral shaped path.

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